

VOLTAGE MEASURING METHOD, ELECTRICAL TEST METHOD AND
APPARATUS SEMICONDUCTOR DEVICE MANUFACTURING METHOD AND
DEVICE SUBSTRATE MANUFACTURING METHOD

ABSTRACT OF THE DISCLOSURE

A simplified test method is established not to use a probe on the interconnection, and a test apparatus is provided which uses the test method. The primary coil possessed by a testing substrate and the secondary coil possessed by an
5 OLED panel are superposed together through a constant spacing. An alternating current signal is inputted to the primary coil to generate an electromotive force on the secondary coil due to electromagnetic induction. By using the electromotive force, the pixel possessed by the OLED panel is operated. A pixel electrode and a testing electrode are superposed together through a constant spacing. By
10 monitoring an alternating current voltage generated on the testing electrode, a faulty point is detected. Furthermore, an operating state of each pixel may be confirmed by monitoring an alternating current voltage generated on the testing electrode while changing the position of the testing electrode.

(Fig. 3)



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AMENDED SHEET